



环形正负电子对撞机  
Circular Electron Positron Collider

# Vertex Tracker Detector

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On behalf of the study group

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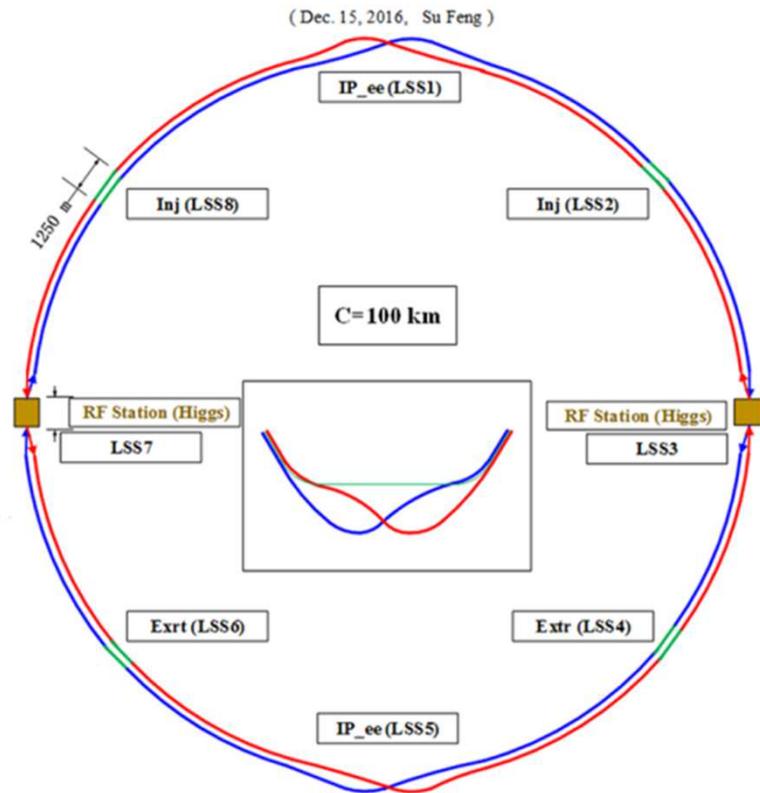
**Apologize if anybody missed from the list**

# Outline:

- *Requirements and challenges*
- *Baseline design and performance studies*
- *Sensor technology options*
- *Mechanics and Integration*
- *R&D activities*
- *Summary*

# Reminder: CEPC Beam Timing

**Circular  $e^+e^-$  Higgs (Z) factory**    two detectors, 1M ZH events in 10yrs  
 $E_{\text{cm}} \approx 240\text{GeV}$ , luminosity  $\sim 2 \times 10^{34} \text{ cm}^{-2}\text{s}^{-1}$ , ( $1.6 \times 10^{35} \text{ cm}^{-2}\text{s}^{-1}$  at the Z-pole)



**Bunch spacing**  $0.68 \mu\text{s}$  @ H(240)  
 $0.21 \mu\text{s}$  @ W(160)  
 $25 \text{ ns}$  @ Z(91)

**Fully Partial Double Ring - 100Km**

# Vertex Detector Requirements

- Efficient tagging of heavy quarks (b/c) and  $\tau$  leptons  
→ impact parameter resolution

$$\sigma_{r\phi} = 5 \oplus \frac{10}{p(\text{GeV}) \sin^{3/2} \theta} (\mu\text{m})$$

- Detector system requirements:
  - $\sigma_{\text{SP}}$  near the interaction point:  $< 3 \mu\text{m}$  →  $\sim 16 \mu\text{m}$  pixel pitch
  - material budget:  $\leq 0.15\% X_0/\text{layer}$  → power consumption  $< 50 \text{mW}/\text{cm}^2$ , if air cooling used
  - first layer located at a radius:  $\sim 1.6 \text{ cm}$
  - pixel occupancy:  $\leq 1 \%$  →  $\sim \mu\text{s}$  level readout

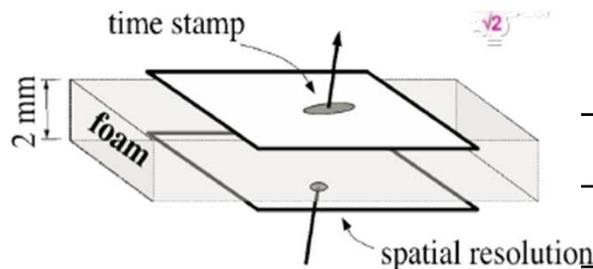
\* **Radiation tolerance:** see slide 9

\* **Time stamp:** needed for short bunch spacing

# Baseline Vertex Detector Layout

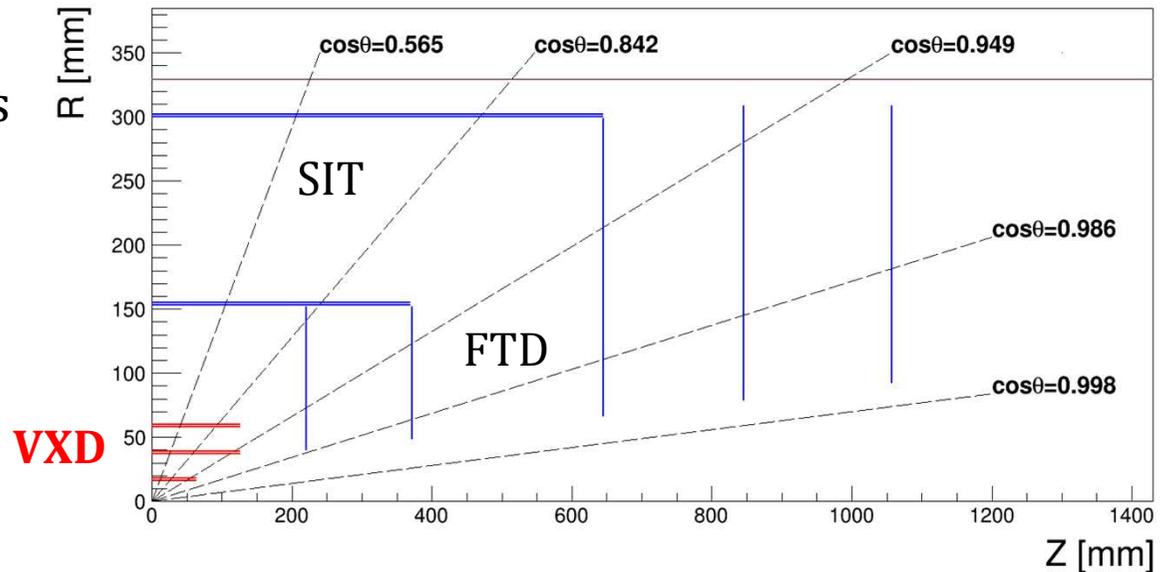
**VXD:**  $B=3T$

- 3 layers of double-sided pixels
- $\sigma_{SP}=2.8\mu\text{m}$  in L1
- Faster pixel sensor in L2, to provide time-stamp
- Polar angle  $\theta\sim 15$  degrees
- Total number of pixels: 690M



## VXD parameters

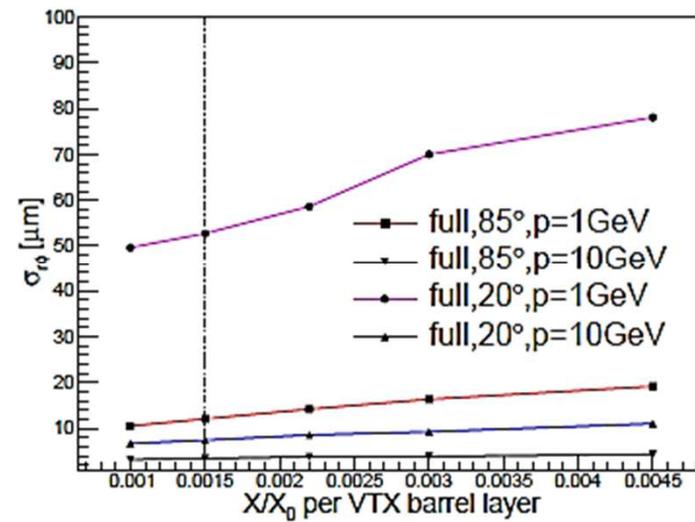
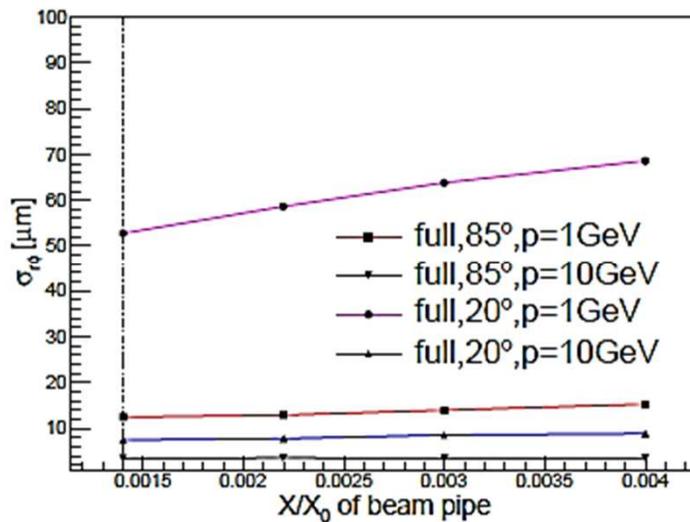
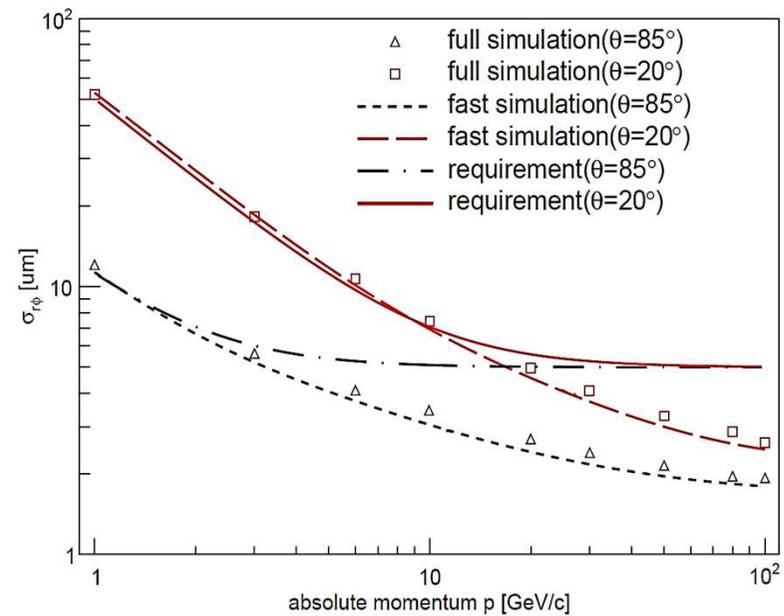
	R (mm)	z  (mm)	cos $\theta$	$\sigma_{sp}$ ( $\mu\text{m}$ )
Layer 1	16	62.5	0.97	2.8
Layer 2	18	62.5	0.96	6
Layer 3	37	125.0	0.96	4
Layer 4	39	125.0	0.95	4
Layer 5	58	125.0	0.91	4
Layer 6	60	125.0	0.90	4



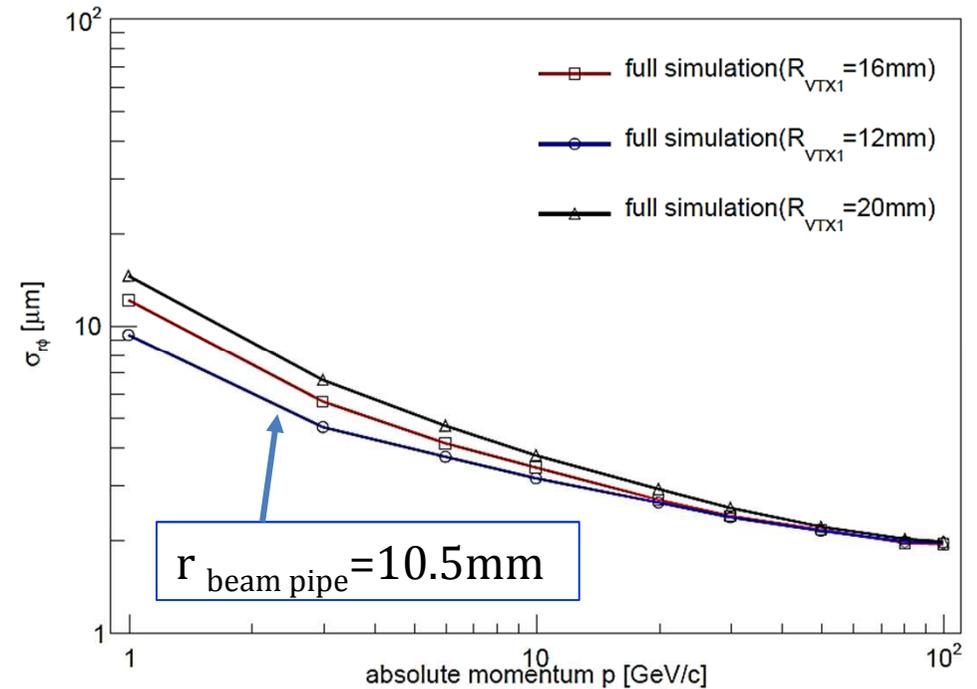
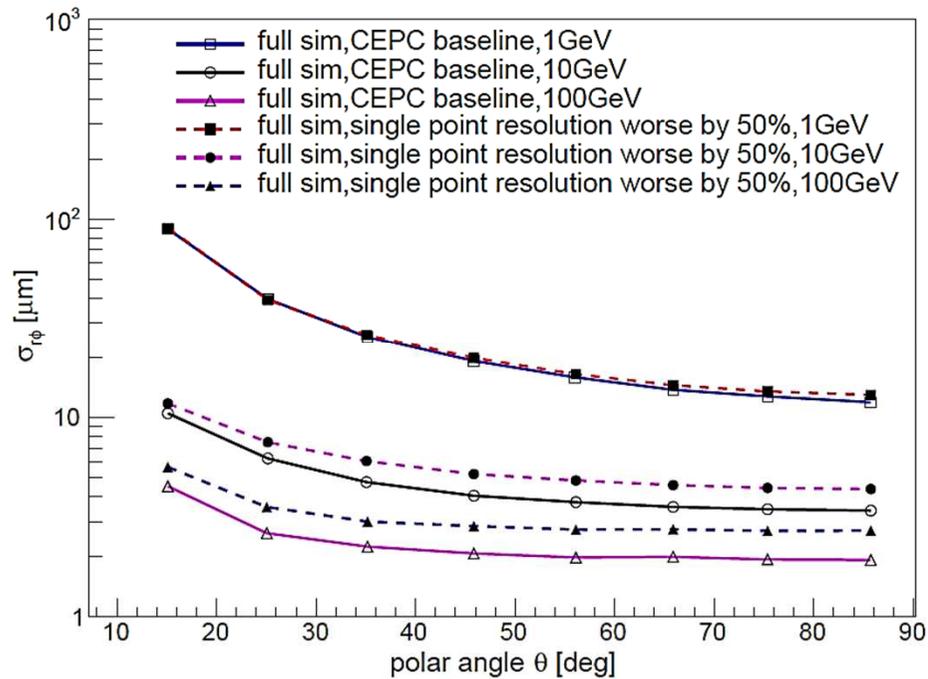
# Performance Studies – IP Resolution

Performance of the baseline configurations with fast and full simulation

Sensitivity to material budget with full simulation



# Performance Studies – IP Resolution



Sensitivity to single-point resolution and innermost radius with full simulation

# Beam-Induced Radiation Backgrounds

	H (240)	W (160)	Z (91)	
Hit Density [hits/cm <sup>2</sup> ·BX]	2.4	2.3	0.25	
TID [MRad/year]	0.93	2.9	3.4	
NIEL [10 <sup>12</sup> 1 MeV $n_{eq}$ /cm <sup>2</sup> ·year]	2.1	5.5	6.2	

**Table 9.4:** Summary of hit density, total ionizing dose (TID) and non-ionizing energy loss (NIEL) with combined contributions from pair production and off-energy beam particles, at the first vertex detector layer ( $r = 1.6$  cm) at different machine operation energies of  $\sqrt{s} = 240, 160$  and  $91$  GeV, respectively.

	H(240)	W(160)	Z(91)
Hit density (hits · cm <sup>-2</sup> · BX <sup>-1</sup> )	2.4	2.3	0.25
Bunching spacing ( $\mu$ s)	0.68	0.21	0.025
Occupancy (%)	0.08	0.25	0.23

**Table 4.2:** Occupancies of the first vertex detector layer at different machine operation energies: 240 GeV for  $ZH$  production, 160 GeV near  $W$ -pair threshold and 91 GeV for  $Z$ -pole.

detector occupancy **<1%**, assuming 10  $\mu$ s of readout time for the silicon pixel sensor and an average cluster size of 9 pixels per hit.

# Sensor Technology Options

Technology	Examples	Small pixels	Low mass	Low power	Fast timing
Monolithic CMOS MAPS	Mimosa CPS	++	++	++	-
Integrated sensor/amplif. + separate r/o	DEPFET, FPCCD	+ / ++	0	+	-
Monolithic CMOS with depletion	HV-CMOS, HR-CMOS	+	++	0	+
3D integrated	Tezzaron, SOI	++	+	0	++
Hybrid	CLICpix+planar sensor, HV-CMOS hybrid	+	0	+	++

Ref: Recent developments in LC vertex and tracking R&D, Dominik Dannheim, LCWS 2015

Many technologies from ILC/CLIC could be referred.  
 BUT, unlike the ILD/CLIC, the CEPC detector will operate in **continuous mode**. → **without power-pulsing**

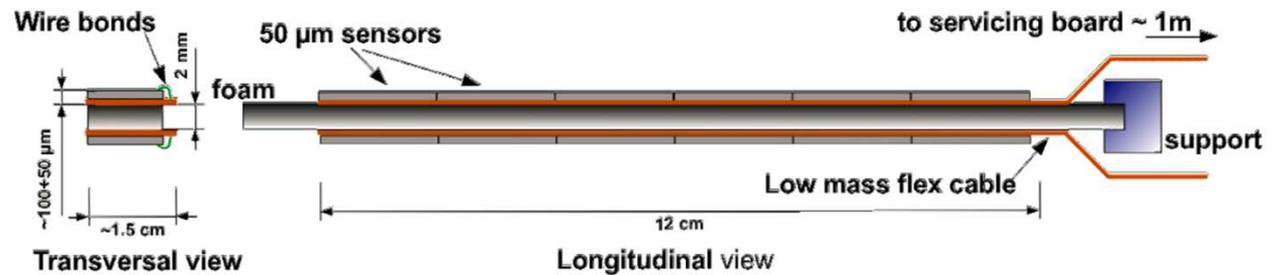
# Sensor Technology Options

## Possible technologies for CEPC vertex

- **HR-CMOS** sensor with a novel readout structure (ALPIDE @ ALICE-ITS upgrade)
  - relatively mature technology
  - $<50\text{mW}/\text{cm}^2$  expected
  - Capable of readout every  $\sim 4\mu\text{s}$
- **SOI** sensor with similar readout structure
  - Fully depleted HR substrate, potential of  $16\mu\text{m}$  pixel size design
  - Full CMOS circuit
- **DEPFET**: possible application for inner most vertex layer
  - small material budget, low power consumption in sensitive area
- **3D-IC**: ultimate detector, but not mature enough

# Mechanics and Integration

- **Double-sided ladder**  
- PLUME design concept
- **Cooling**  
- to be considered



Vertex detector	Power dissipation	Cooling method	Material budget requirement/layer
Alice ITS	300 mW/cm <sup>2</sup>	water	0.3%
STAR PXL	170 mW/cm <sup>2</sup>	air	0.39%
ILD vertex	< 120 mW/cm <sup>2</sup> (CPS and DEPFET)	air or N <sub>2</sub>	0.15%
	35 W inside cryostat (FPCCD)	two-phase CO <sub>2</sub>	
BELLE-II PXD	20 W for sensor and SWITCHER	Air	0.2%
	180 W on each end	CO <sub>2</sub>	

**Table 4.3:** Cooling methods for several vertex detector designs. The chip power dissipation, coolant type and corresponding material budget requirement per sensor layer are indicated. The active CO<sub>2</sub> cooling adds additional material in the forward region, outside the sensitive area. For the ILD FPCCD option, this additional material budget is 0.3%  $X_0$  averaged over the end-plate region, while for the BELLE-II PXD, it is  $\sim 0.1 - 0.2\%$   $X_0$  per layer.

# R&D Activities in China

## Initial sensor R&D targeting on

- Pixel single point resolution  $<3 - 5\mu\text{m}$
- Power consumption at the current level  $<100\text{mW}/\text{cm}^2$
- Integration time  $10-100\mu\text{s}$

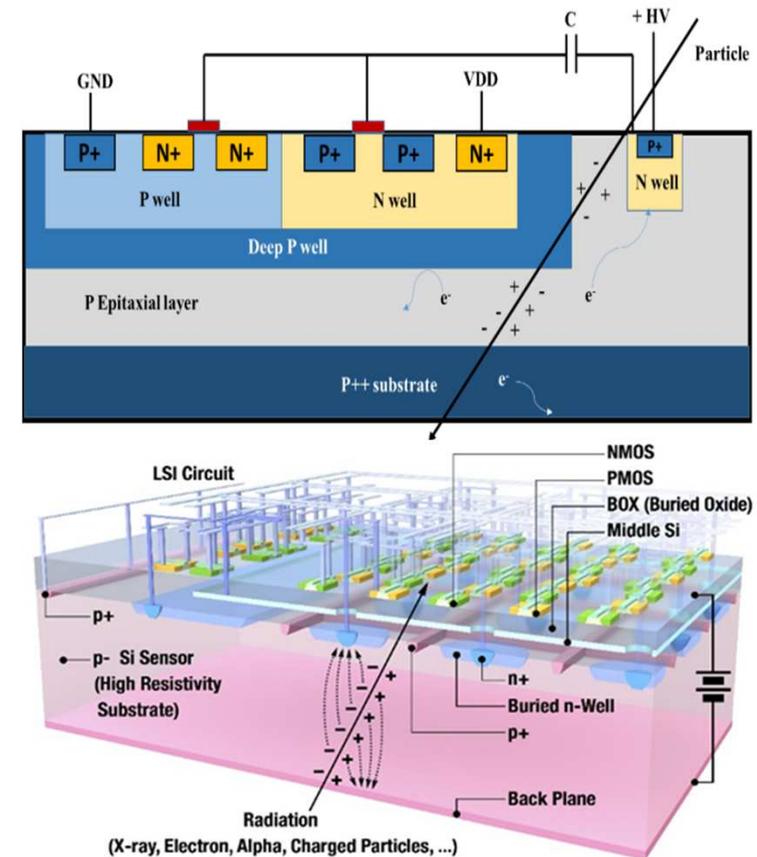
## Two monolithic pixel technologies

### ➤ CMOS pixel sensor (CPS)

- *TowerJazz CIS 0.18  $\mu\text{m}$  process*
- *Quadruple well process*
- *Thick ( $\sim 20\mu\text{m}$ ) epitaxial layer*
- *with high resistivity ( $\geq 1\text{ k}\Omega\cdot\text{cm}$ )*

### ➤ SOI pixel sensor

- *LAPIS 0.2  $\mu\text{m}$  process*
- *High resistive substrate ( $\geq 1\text{ k}\Omega\cdot\text{cm}$ )*
- *Double SOI layers available*
- *Thinning and backside process*



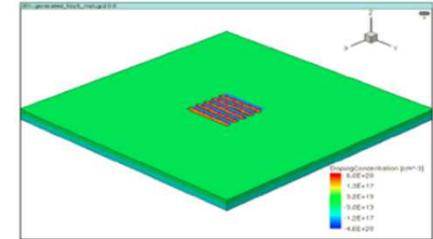
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# CMOS Pixel Sensor – 1<sup>st</sup> Design

- **Sensor design & TCAD simulation**

Y.Zhang, et al, NIMA 831(2016)99-104

- Different sensor diode geometries, epitaxial-layer properties and radiation damage



- **JadePix1 submission in Nov. 2015**

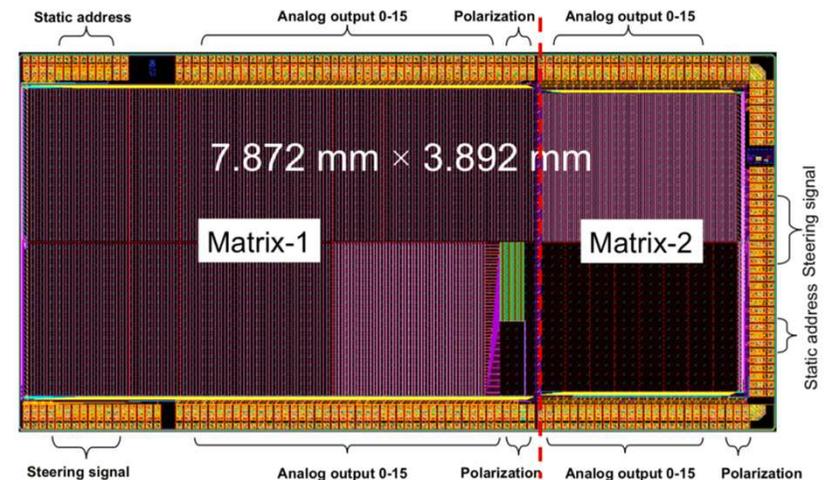
Y. Zhang, Y.Zhou, et al (IHEP, SDU)

- Exploratory prototype, analog pixel, rolling shutter readout mode
- **Sensor optimization** and radiation tolerance study
- sensing node AC-coupled to increase biased voltage

- **Sensor characterization**

IHEP

- Noise level
- Charge collection efficiency
- Irradiation with Neutron
- Test beam in Aug. 2018



# CMOS Pixel Sensor – 2<sup>nd</sup> Design

**Design goal:** digital readout pixel sensor with

- *Single point resolution better than  $5\mu\text{m}$*
- *Power consumption  $< 80\text{ mW/cm}^2$*
- *Integration time  $< 100\mu\text{s}$*

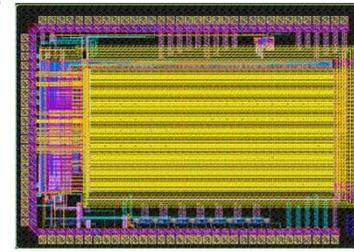
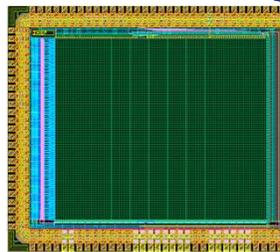
**Joint effort of CCNU and IHEP**

## Design submission in May 2017

- Two prototypes with **digital pixels** (in-pixel discriminator)
- Two different readout schemes: **rolling shutter** & **asynchronous**

**JadePix2:** Y.Zhou (IHEP)

- Pixel size:  $22\mu\text{m} \times 22\mu\text{m}$
- Two different pixel version with higher biased voltage
- Test in lab ongoing



**MIC4:** P.Yang(CCNU)

Y.Zhang (IHEP)

- Pixel size:  $25\mu\text{m} \times 25\mu\text{m}$
- Two different pixel front-end with Matrix readout architecture
- Test in lab ongoing

# SOI Pixel Sensor

- **First submission (CPV1) in June 2015**

Y. Lu (IHEP)

- 16\*16  $\mu\text{m}$  with in-pixel-discrimination
- Double-SOI process for shielding and radiation enhancement

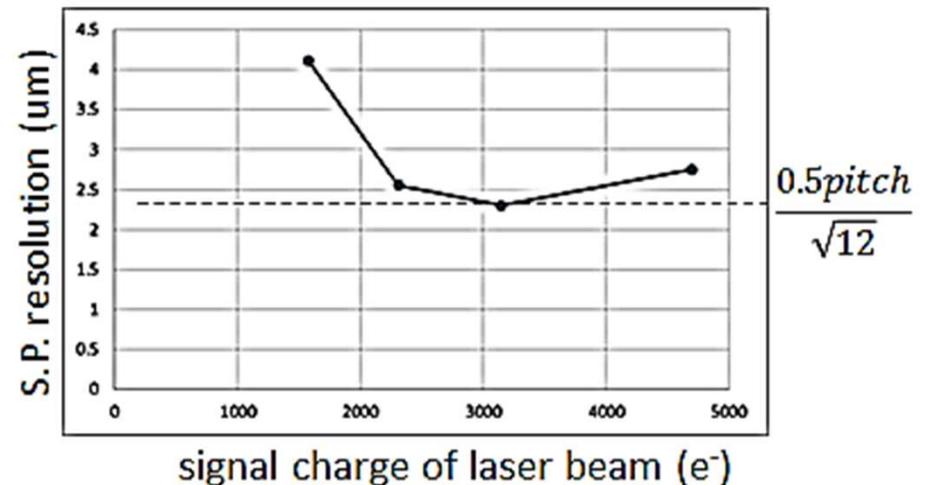
- **Second submission (CPV2) in June 2016**

Y. Lu, Y.Zhou (IHEP)

- In-pixel CDS stage inserted
- To improve RTC and FPN noise
- To replace the charge injection threshold

## CPV2 performance

- Thinned down to 75 $\mu\text{m}$  thick
- Temporal noise  $\sim 6e^-$
- Threshold dispersion (FPN)  $\sim 114e^-$
- Single point resolution measurement under infrared laser beam



# Future Plan on R&D

- Further optimization study of vertex system
- Novel readout scheme exploration
- Large area pixel array design
- Radiation hardness and time-stamp sensor design
- Prototype development within 5 years
- Small ( $16\mu\text{m} \times 16\mu\text{m}$ ) pixel, targeting on  $3\mu\text{m}$  single point resolution
  - To explore 3D connection technology by designing the in-pixel digital logic in a separated tier
  - Or to look for any new process

# Summary

- CDR finished with baseline design
- Critical technologies listed
- R&D project started along the baseline design specifications
  - *in-pixel electronics, small pixel size*
  - *new asynchronous readout architecture*
- Collaboration with international teams
- Going to TDR for next step
- Expertise demanding

Many thanks to all members of CEPC Physics and Detector working group who made significant efforts to prepare the CDR !

**Thank you for your attention!**